Contents

1. Introduction **1**

2. Design and Preparation of Nb/InAs(2DES)/Nb Josephson Junctions **5**
2.1. Junction Types 5
2.2. Sample Preparation 7
2.2.1. Josephson Field-Effect Transistors on Bulk InAs 7
2.2.2. Josephson Field-Effect Transistors on HEMT Heterostructure Substrates 10
2.2.3. Overlap Junctions on Bulk InAs 12

3. Transport Measurements of Nb/InAs(2DES)/Nb Josephson Junctions **14**
3.1. Measurement Procedures 14
3.2. Miniaturization of Nb/InAs(2DES)/Nb Josephson Junctions 18
3.3. Comparison of Etching Techniques of InAs Heterostructures 21

4. Current-Phase Relationship **28**
4.1. Theory of the Current-Phase Relationship 29
4.2. Current-Phase Relationship Measurement Technique 31
4.2.1. Principle 32
4.2.2. Limitations 34
4.2.3. Experimental Realization 35
4.3. Design and Preparation of Samples for Current-Phase Measurements . . 35
4.3.1. Interferometer Loops 37
4.4. Results and Discussion 41
4.4.1. Current-Phase Relationship of Overlap Junctions 41
4.4.2. Current-Phase Relationship of Josephson Field-Effect Transistors 44

5. Summary and Conclusion **48**

Appendices **52**

A. Niobium Sputter Deposition System **52**
A.1. Basic Operation 52
A.2. Optimization of Niobium Films 54
A.3. Modifications for Optimized Josephson Junctions 56
A.4. Cathode Corrosion 57

B. List of Publications **59**
B.1. Conference Contributions 59
B.2. Paper A 59
B.3. Paper B 64
B.4. Paper C 70

C. Preparation Parameters **75**

D. Glossary **78**

Bibliography **80**

E. Acknowledgments **87**